

Substitute for forms 1449A/PTO &amp; 1449B/PTO

ATTORNEY'S DKT NO.  
024445-377APPLICATION NO.  
10/653,244INFORMATION DISCLOSURE  
STATEMENT BY APPLICANTAPPLICANT  
Anders HÖRLING et al.FILING DATE  
September 3, 2003GROUP  
1772

## U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (If known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
A	5,272,014		LEYENDECKER et al.	12-21-1993
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	5,503,912		SETOYAMA et al.	04-02-1996
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	6,103,357		SELINDER et al.	08-15-2000
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## FOREIGN PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (If known)	Country	Date of Publication (MM-DD-YYYY)	Translation Yes	No
A	1 219 723	A2	EP	07-03-2002		
	11310867		JP	11-09-1999		
	9295204		JP	11-18-1997		

## NONPATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
A	Hermann A. Jehn et al., MORPHOLOGY AND PROPERTIES OF SPUTTERED (Ti,Al)N LAYERS ON HIGH SPEED STEEL SUBSTRATES AS A FUNCTION OF DEPOSITION TEMPERATURE AND SPUTTERING ATMOSPHERE, J. Vac. Sci. Technol. A 4 (6), 2701 (1986)
	O. Knotek et al., ON STRUCTURE AND PROPERTIES OF SPUTTERED Ti AND Al BASED HARD COMPOUND FILMS, J. Vac. Sci. Technol. A 4 (6), 2695 (1986)
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	W.-D. Münz, TITANIUM ALUMINIUM NITRIDE FILMS - A NEW ALTERNATIVE TO TIN COATINGS, Int. Conf. Met. Coat., San Diego, USA (1986)
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	D. McIntyre et al., OXIDATION OF METASTABLE SINGLE-PHASE POLYCRYSTALLINE Ti <sub>0.5</sub> Al <sub>0.5</sub> N FILMS: KINETICS AND MECHANISMS, J. App. Phys. 67 (3), 1542 (1990)
A	H. Holleck, METASTABLE COATINGS - PREDICTION OF COMPOSITION AND STRUCTURE, Surf. and Coat. Technol. 36, 151 (1988)

Examiner Signature

Date Considered

9/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.

# **SECOND INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 1 of 1

**Complete if Known**

Application Number	10/653,244
Filing Date	September 3, 2003
First Named Inventor	Horling, Anders et. al.
Examiner Name	Unassigned
Attorney Docket Number	024445-377

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**U.S. PATENT DOCUMENTS**

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
A	2002/028323	A1	NAKAMURA et al.	03-07-2002

**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	Translation	
					Yes	No

**NON-PATENT LITERATURE DOCUMENTS**

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
A	L. KARLSSON et al., "Influence of residual stresses on the mechanical properties of $TiC_xN_{1-x}$ ( $x = 0, 0.15, 0.45$ ) thin films deposited by arc evaporation", <i>Thin Solid Films</i> , 371 (2000) pp. 167-177.
sh	S. MENZEL et al., "Phase transitions in PACVD-(Ti,Al)N coatings after annealing", <i>Surface and Coatings Technology</i> , 124 (2000), pp. 190-195.

Examiner Signature

Date Considered

9/05

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.